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To HYUNUKKIM@uta.edu

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17/06/2008 15:00

bcc

Subject Re: Fw: About the permission to use sem picture in the journal

Julie O'Donnell/IOPPUBUSA/IOPP

--- Forwarded by Julie O'Donnell/IOPPUBUSA/IOPP on 06/17/2008 08:33 AM ---

"Kim, Hyunuk"
<HYUNUKKIM@uta.edu>

To <info@ioppubusa.com>

06/17/2008 01:42 AM

cc

Subject About the permission to use sem picture in the journal

Hi.

My name is HyunUk Kim. And i am grad student in UT arlington.

I hope to use SEM picture in the journal.

Can you tell procedure to do this?

Name of journal : Journal of Micromechanics and Microengineering.

Author : K. P. Larsen, ~~and~~ J. T. Ravnkilde and O. Hansen

Title of paper : Investigation of the isotropic etch of an ICP source

Volume: 15

Page : 875 *4 April*Published : ~~March~~ 2005 *pp 873-882*

Figure No.: Figure 4 SEM image of the cross section of an etched trench.

Thank you in advance.

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2008-06-17 오전 11:08에 회신했습니다.

Kim, Hyunuk

보낸 사람: Ron Staut [rstaut@americanpiezo.com]

보낸 날짜: 2008-06-17 (화) 오전 7:07

받는 사람: Kim, Hyunuk

참조:

제목: Figure 1.1 in "Piezoelectric Ceramics: Principles and Applications"

첨부 파일:

Dear Hyunuk,

You have our permission to use the subject figure in your thesis.

Best of luck in your academic and career endeavors.

Best regards,

Ronald Staut, Ph.D.

VP Technology

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Journal of electrochemical society,
Nov. 1990, Vol. 137, No. 11, p 3025
Table A-1 <100> silicon etch rates in [um/h] for
various KOH concentration and etch temperatures as calculated
from Eq. [A-1] by setting $E_a = 0.595 \text{ eV}$ and $k_a = 2480 \text{ um/h} \cdot (\text{mol/L})^{0.25}$
Author: Jun Li
Signature: _____ Date: 6/18/08
Name: Hyunlic Kim
Address: 816 Misty Brook Dr #278
Arlington, TX 76013

Telephone: 817-501-4370 Fax: 817-272-2538

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보낸 날짜: 2008-06-20 (금) 오후 2:21

받는 사람: Kim, Hyunuk

참조:

제목: Re: FW: About the permission to use SEM image in the journal

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Title of paper : Deep anisotropic etching of silicon

Volume: 17(4)

Page :2271

Published : Jul/Aug 1999

Figure No.: Figure 2 SEM picture of a 2 um, 36um trench etched in silicon at an average etch rate of 3.6um/min

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>>> "Kim, Hyunuk" <HYUNUKKIM@uta.edu> 06/18/08 3:11 PM >>>  
Hi.

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Title of paper : Deep anisotropic etching of silicon  
Volume: 17(4)  
Page :2271  
Published : Jul/Aug 1999  
Figure No.: Figure 2 SEM picture of a 2 um, 36um trench etched in silicon at  
an  
average etch rate of  
3.6um/min

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HyunUk Kim

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From: Scitation Help Desk [<mailto:help@scitation.org>]  
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>>> "Kim, Hyunuk" <HYUNUKKIM@uta.edu> 6/18/2008 12:59 PM >>>  
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My name is HyunUk Kim. And i am grad student in UT arlington.

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Name of journal : Journal of Vacuum science and Technology A  
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